

Geon Lim

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/9010933/publications.pdf>

Version: 2024-02-01

12
papers

61
citations

1684188

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h-index

1588992

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all docs

12
docs citations

12
times ranked

85
citing authors

#	ARTICLE	IF	CITATIONS
1	Resolution enhancement in continuous-wave stimulated emission depletion microscopy by excitation beam with modulated vortex-phased azimuthally polarized light. Optics and Lasers in Engineering, 2020, 134, 106253.	3.8	2
2	Development of a wide-width raster scanning optical system for high-resolution ultraviolet laser direct micro-patterning. Optics and Lasers in Engineering, 2020, 134, 106179.	3.8	3
3	Analysis on improvement in resolution by excitation beam modulation in stimulated emission depletion nanoscopy. Optical Review, 2019, 26, 512-521.	2.0	0
4	Enhanced lateral resolution in continuous wave stimulated emission depletion microscopy using tightly focused annular radially polarized excitation beam. Journal of Biophotonics, 2019, 12, e201900060.	2.3	4
5	Investigation of excitation beam modulation using azimuthal polarization to improve STED resolution. , 2019, , .		0
6	Investigation on improvement of lateral resolution of continuous wave STED microscopy by standing wave illumination. Optics Express, 2018, 26, 9901.	3.4	7
7	Dual-wavelength Fourier ptychography using a single LED. Optics Letters, 2018, 43, 3526.	3.3	12
8	Investigation on achieving super-resolution by solid immersion lens based STED microscopy. Optics Express, 2017, 25, 16629.	3.4	8
9	Low-cost strategy for time delay adjustment of STED microscopy using digital oscilloscope. , 2015, , .		0
10	Experimental demonstration of line-width modulation in plasmonic lithography using a solid immersion lens-based active nano-gap control. Applied Physics Letters, 2015, 106, .	3.3	7
11	Improved Nanogap Servo System Using an Error-Based Disturbance Observer for High-Speed in Solid Immersion Lens-Based Plasmonic Lithography. Japanese Journal of Applied Physics, 2013, 52, 09LG02.	1.5	2
12	High-speed plasmonic nanolithography with a solid immersion lens-based plasmonic optical head. Applied Physics Letters, 2012, 101, .	3.3	16